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UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Seung-un KIM, et al.

Art Unit: 1763

Serial No. 10/800,735

Examiner: S. MacArthur

Filed: March 16, 2004

Confirmation No. 1171

For: APPARATUS AND METHOD FOR SUPPLYING  
CHEMICALS IN CHEMICAL MECHANICAL  
POLISHING SYSTEMS

Attorney Docket No. 239/166 DIV

**REQUEST FOR RECONSIDERATION UNDER 37 C.F.R. § 1.116**  
**AND APPLICANT INITIATED INTERVIEW SUMMARY**

Mail Stop AF  
Commissioner for Patents  
United States Patent and Trademark Office  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

In response to the Office action mailed March 28, 2005, the following remarks and amendments are respectfully submitted in connection with the above-identified application:

**A Listing of the Claims begins on page 2 of this paper.**

**Remarks/Arguments begin on page 6 of this paper.**

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6/24/05